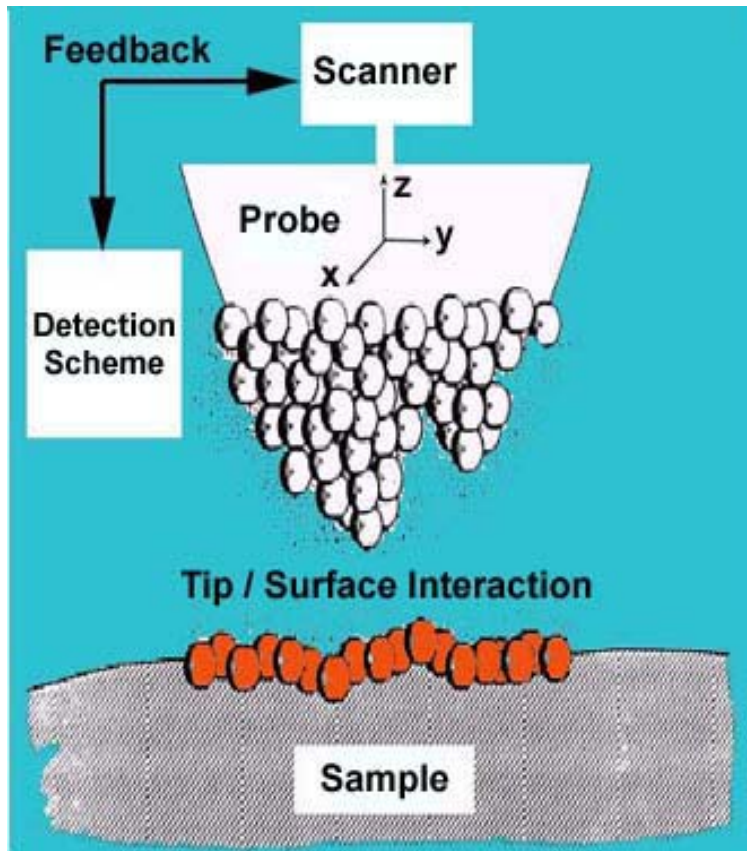


# Scanning Probe Microscopy (SPM)



## Scanning Tunneling Microscopy (STM)

--- G. Binnig, H. Rohrer et al, (1982)

## Near-Field Scanning Optical Microscopy (NSOM)

--- D. W. Pohl (1982)

## Atomic Force Microscopy (AFM)

--- G. Binnig, C. F. Quate, C. Gerber (1986)

## Scanning Thermal Microscopy (SThM)

--- C. C. Williams, H. Wickramasinghe (1986))

## Magnetic Force Microscopy (MFM)

--- Y. Martin, H. K. Wickramasinghe (1987)

## Friction Force Microscopy (FFM or LFM)

--- C. M. Mate et al (1987)

## Electrostatic Force Microscopy (EFM)

--- Y. Martin, D. W. Abraham et al (1988)

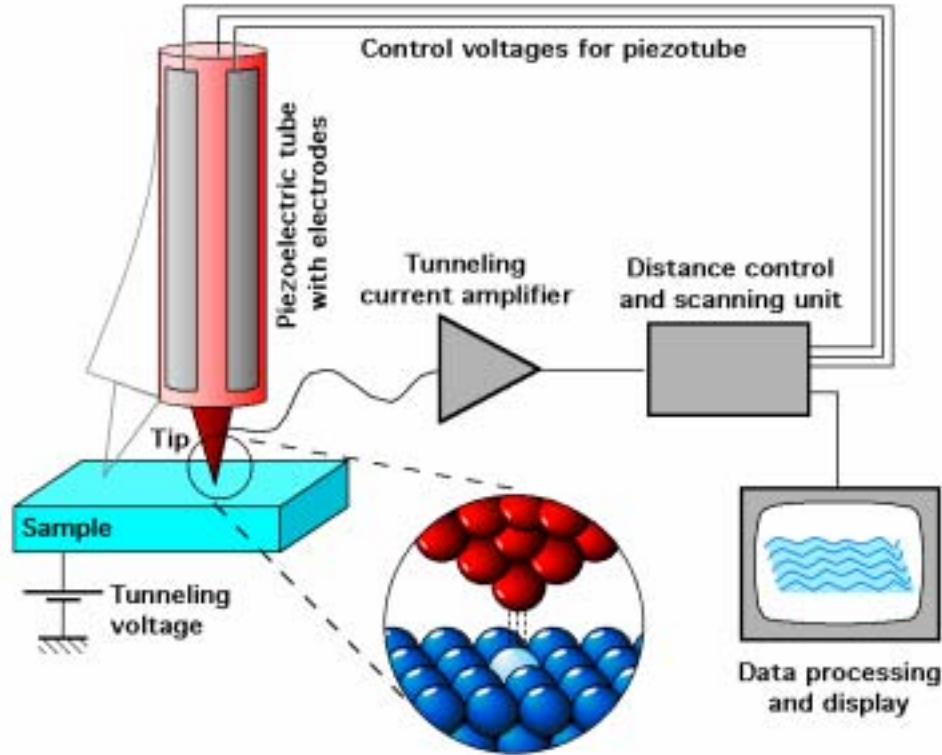
## Scanning Capacitance Microscopy (SCM)

--- C. C. Williams, J. Slinkman et al (1989)

## Force Modulation Microscopy (FMM)

--- P. Maivald et al (1991)

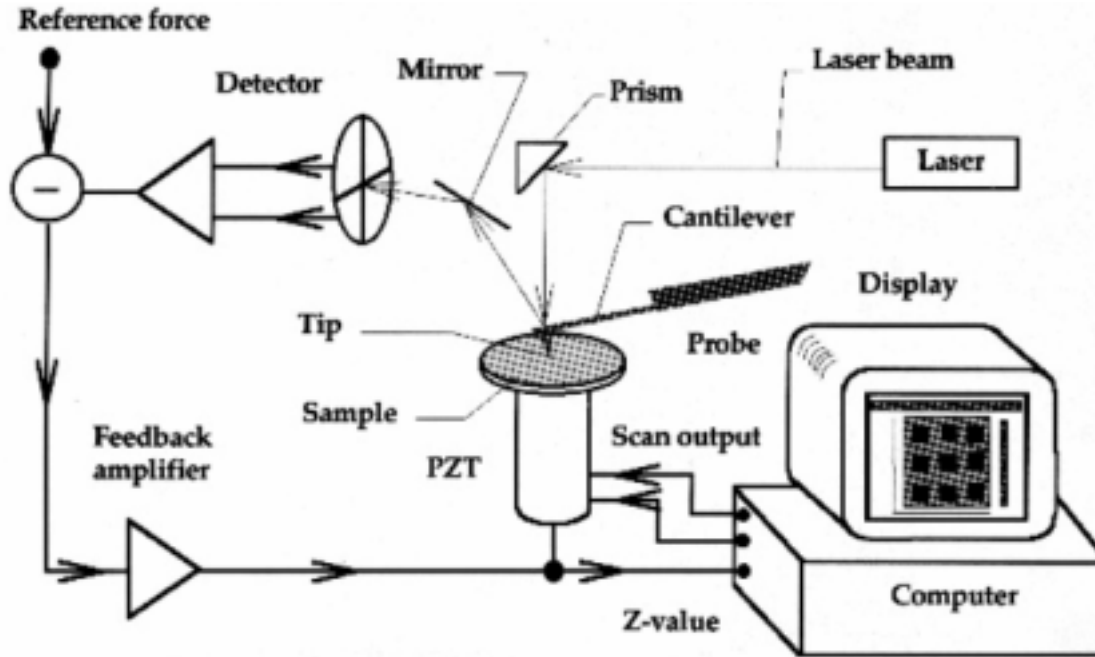
# Scanning Tunneling Microscopy



## References:

1. G. Binnig, H. Rohrer, C. Gerber, and Weibel, Phys. Rev. Lett. **49**, 57 (1982); and ibid **50**, 120 (1983).
2. J. Chen, *Introduction to Scanning Tunneling Microscopy*, New York, Oxford Univ. Press (1993).

# Atomic Force Microscopy (AFM)



$$F = k\Delta z$$

$$F = 10^{-9} - 10^{-6} \text{ N}$$

$$k = 0.1 - 1 \text{ N/m}$$

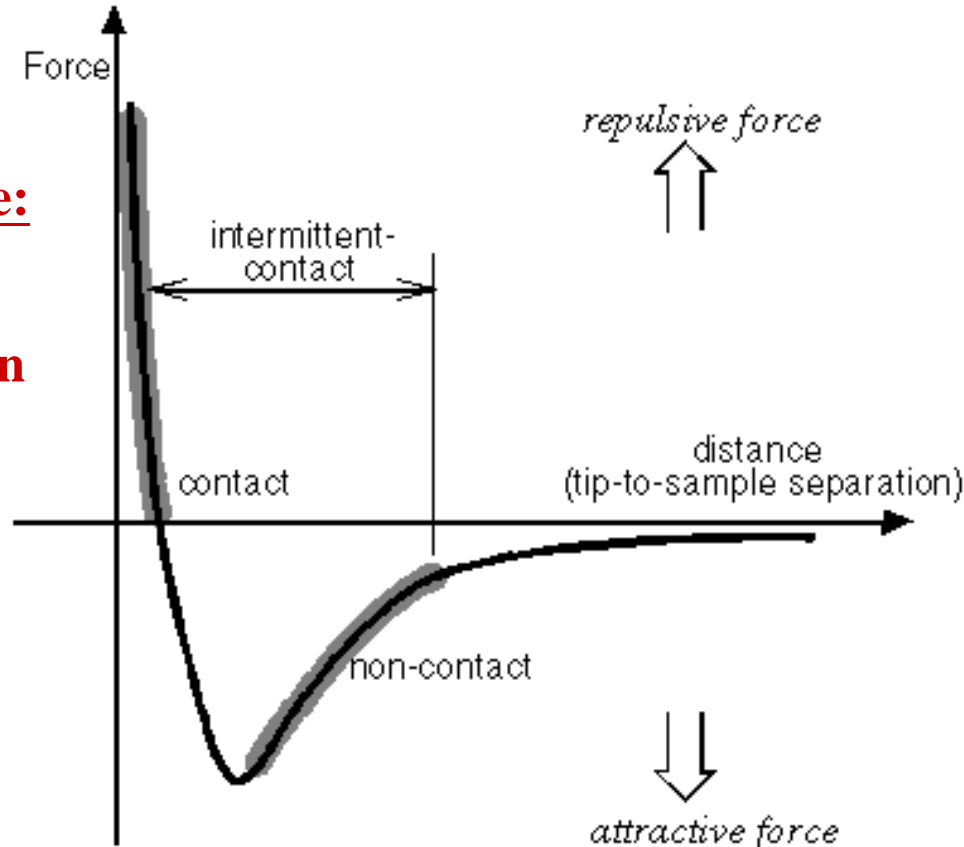
## References:

- G. Binnig, C. F. Quate, and C. Gerber, Phys. Rev. Lett. 56, 930 (1986).
- C. Bustamante and D. Keller, Physics Today, 32, December (1995).
- R. Wiesendanger and H.J. Güntherodt, *Scanning Tunneling Microscopy II*, Springer-Verlag, (1992).

# Interaction between the probe and sample

## Short-range:

- 1) Bonding
- 2) Repulsion

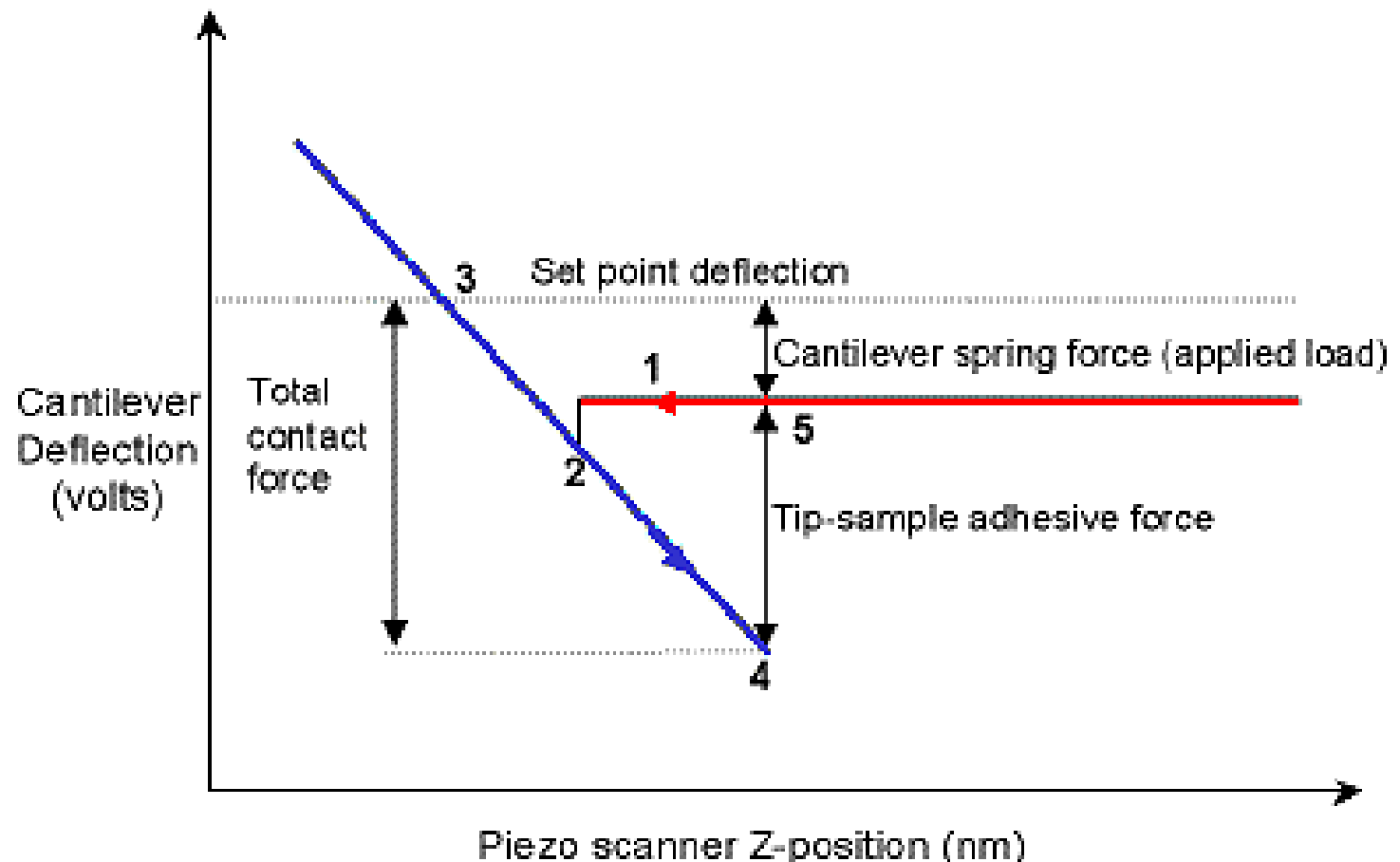


## Long-range:

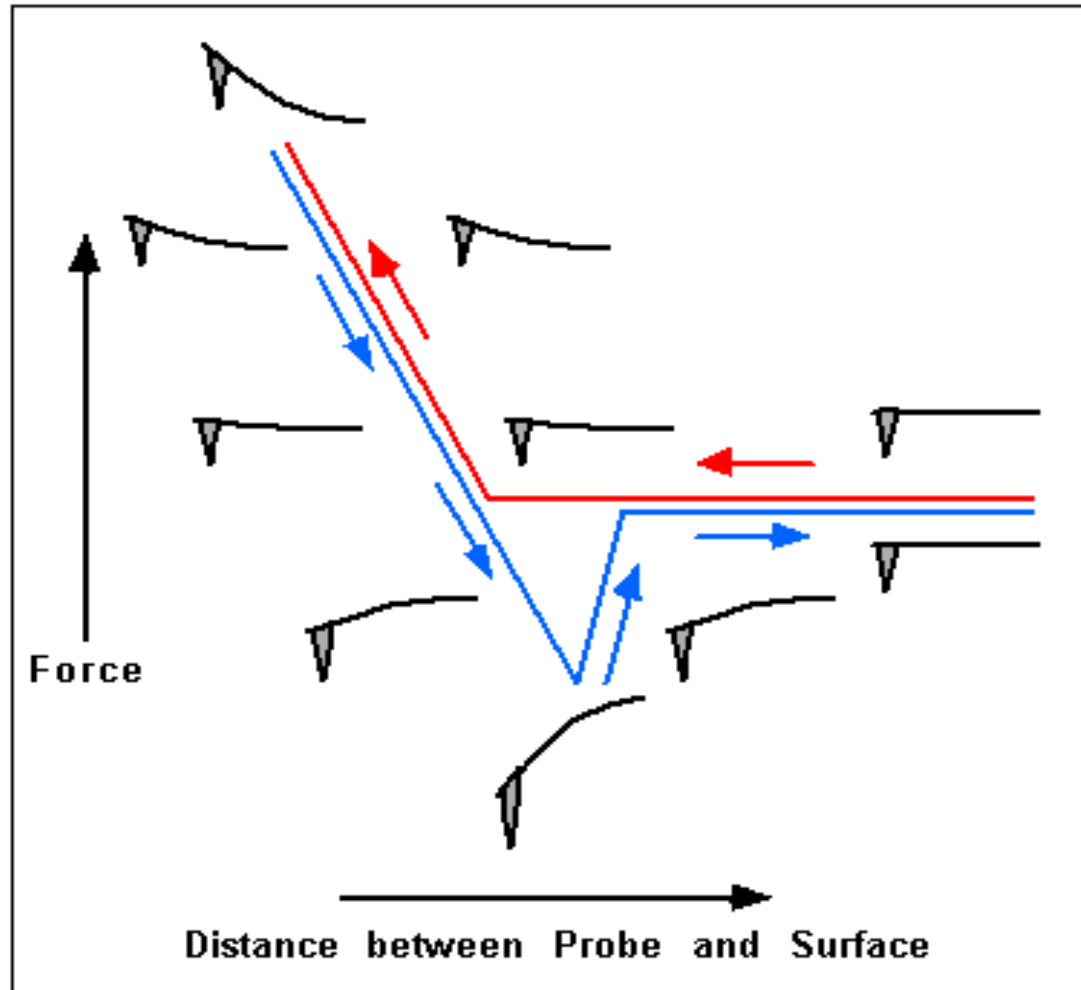
- 1) Van der Waal
- 2) Capillary
- 3) Magnetic
- 4) Electrostatic

Lennard-Jones potential  $\phi(r) = - A/r^6 + B/r^{12}$

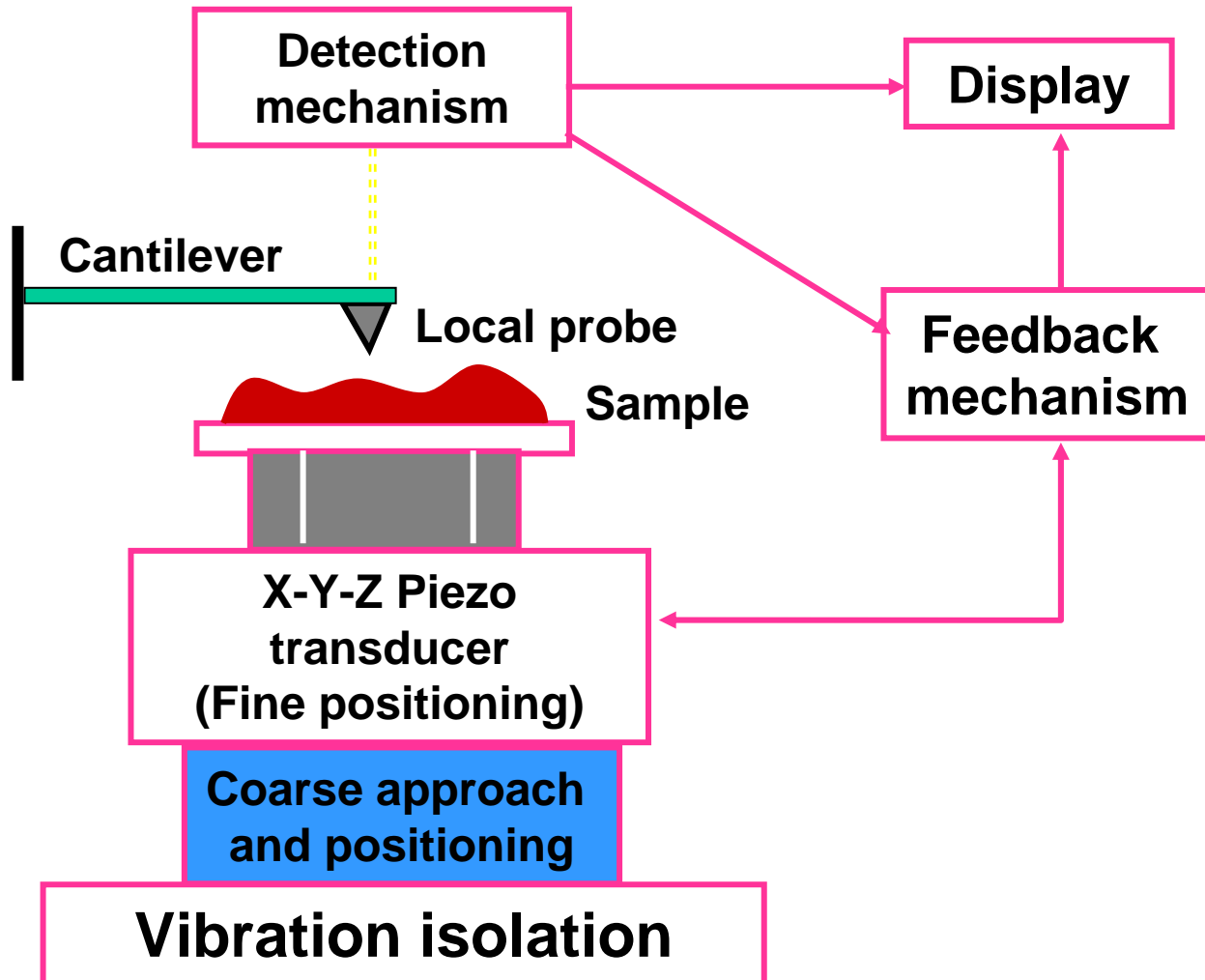
# Deflection of Cantilever vs Piezo displacement



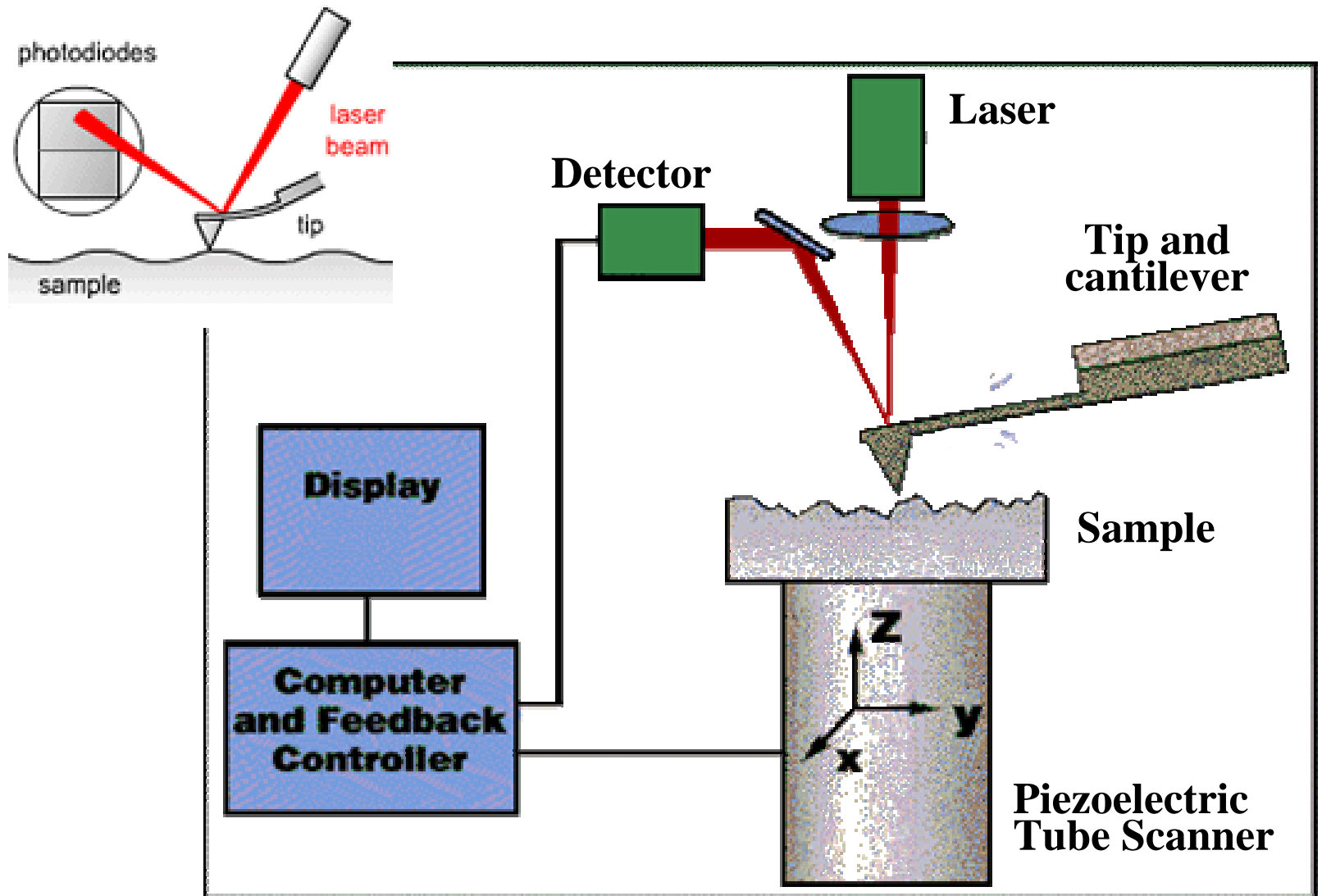
# Reaction of the probe to the force



# Structure of AFM

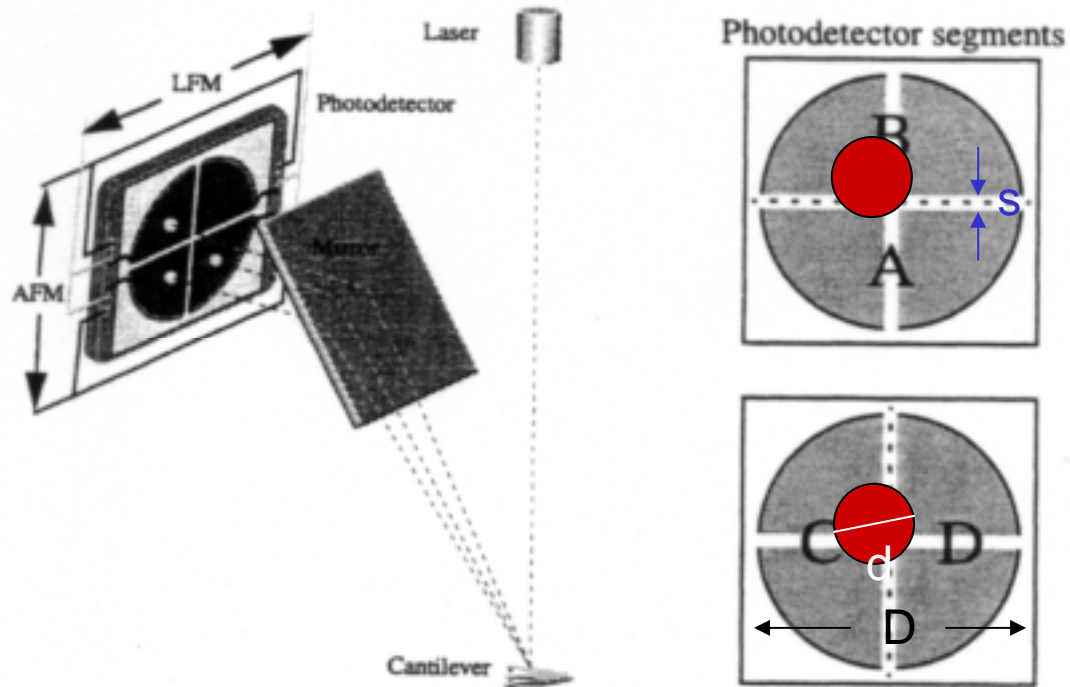


# Core components of AFM



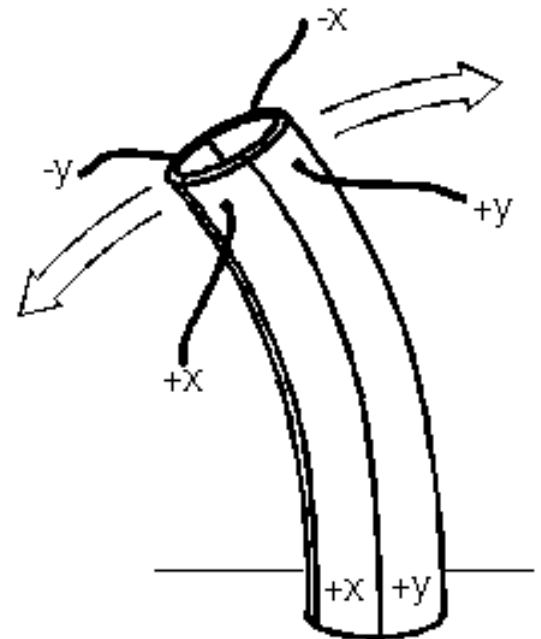
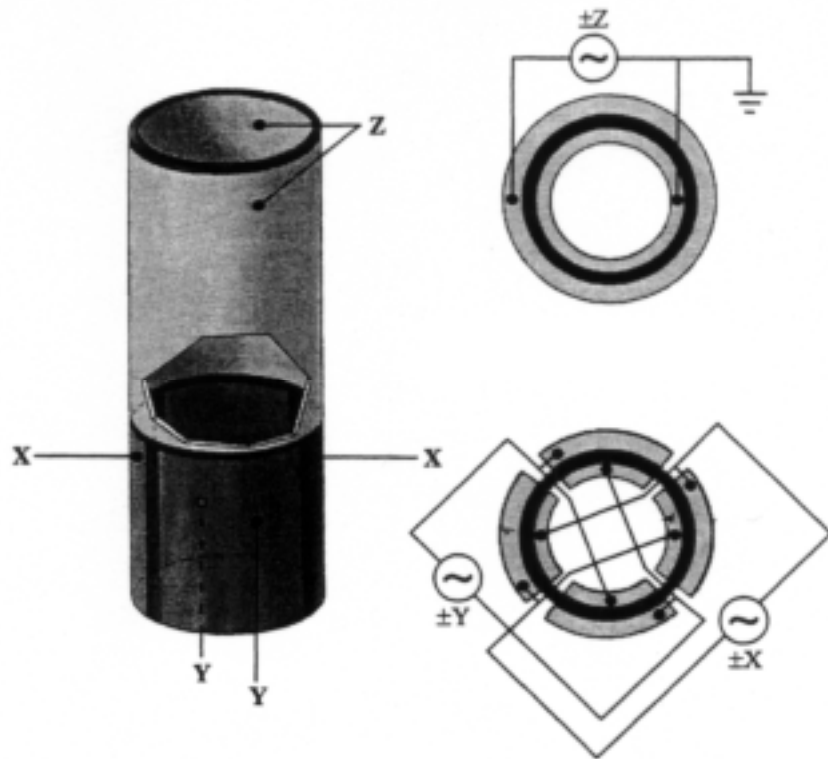


# Position-sensitive Photo Diode (PSPD)

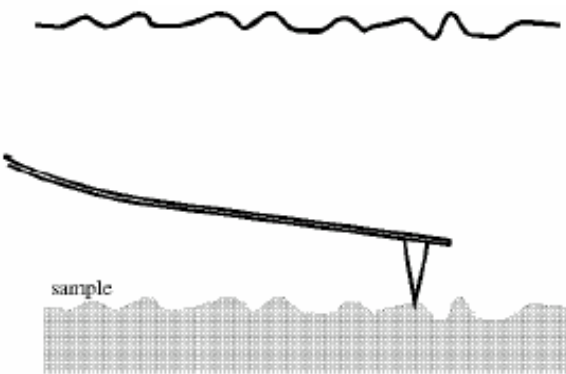


**$D \sim 10\text{mm}$     $d \sim 1\text{mm}$     $s \sim 0.01\text{mm}$**

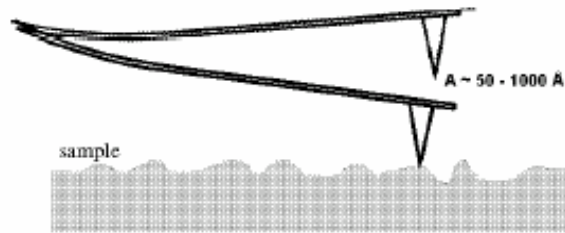
# Piezo Scanner



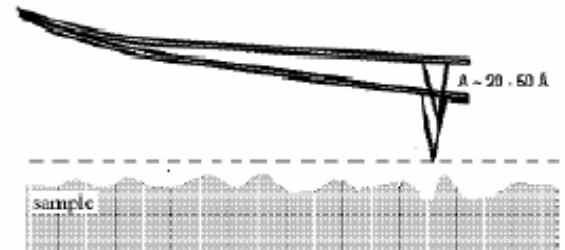
# Three scanning modes of AFM



**Contact  
Mode AFM**



**Semicontact  
Mode AFM**

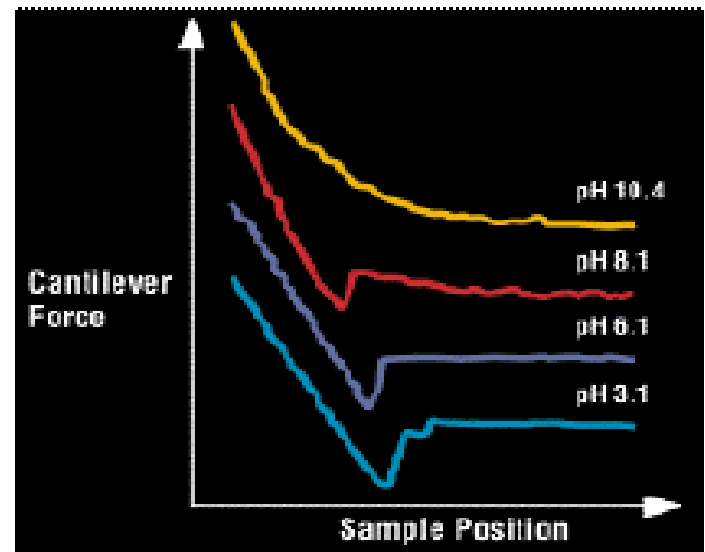
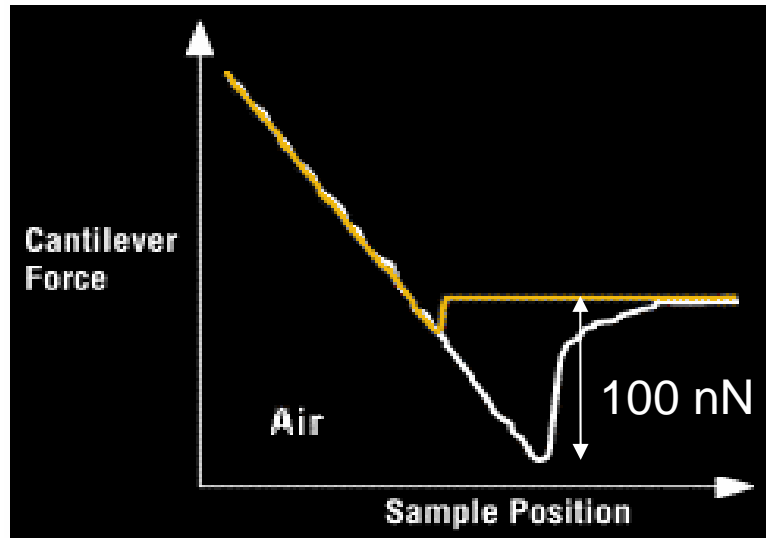
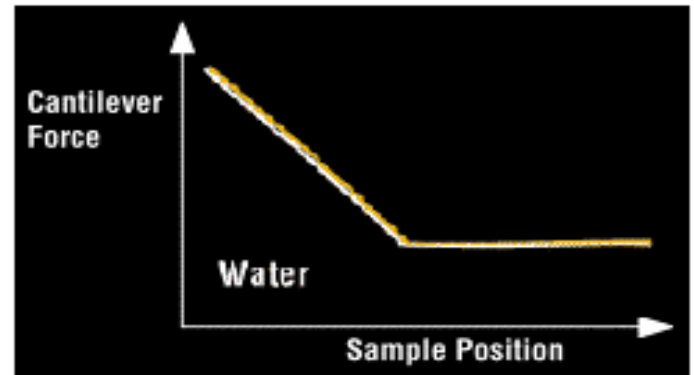
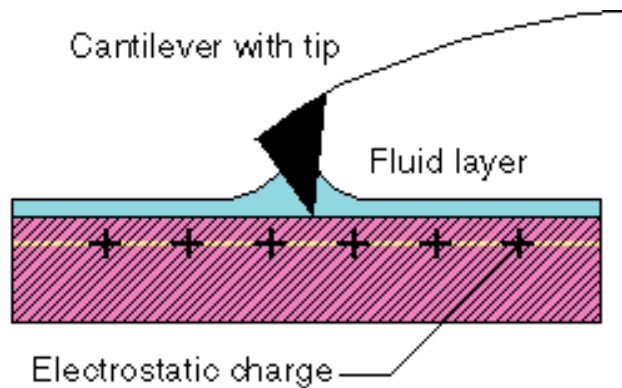


**Non-contact  
Mode AFM**

## Two imaging methods in contact mode

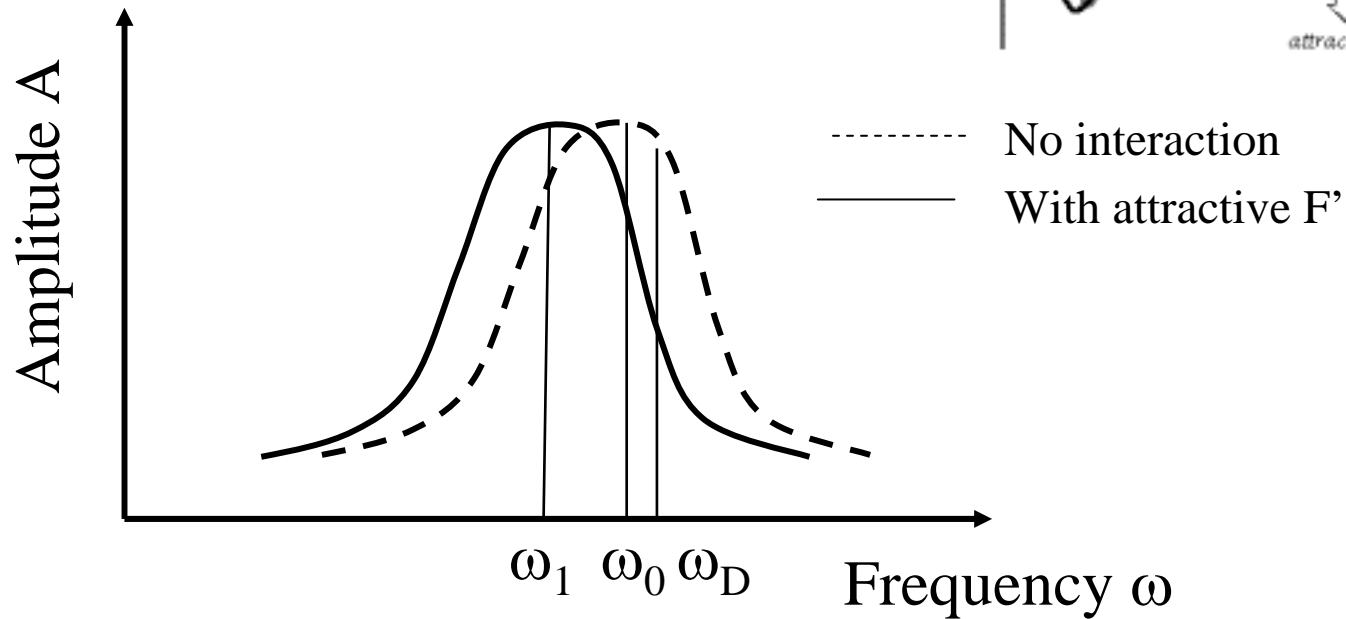
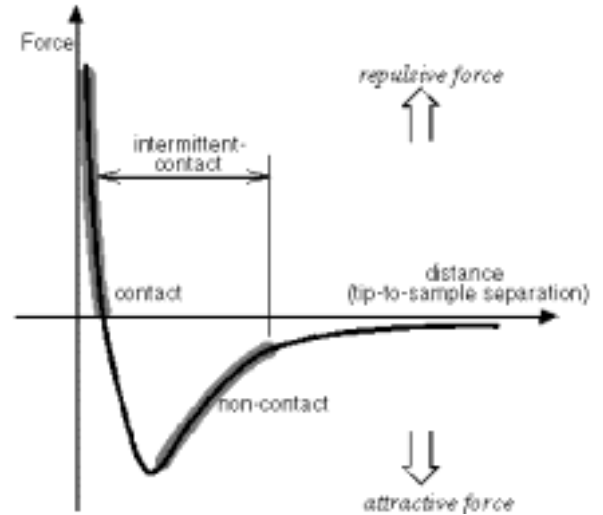
- Constant force method : By using a feedback loop the tip is vertically adjusted in such a way that the force always stays constant. The tip then follows a contour of a constant contact force during scanning. A kind of a topographic image of the surface is generated by recording the vertical position of the tip.
- Constant height method : In this mode the vertical position of the tip is not changed, equivalent to a slow or disabled feedback. The displacement of the tip is measured directly by the laser beam deflection. One of its advantages is that it can be used at high scanning frequencies.

# Problems with the contact mode

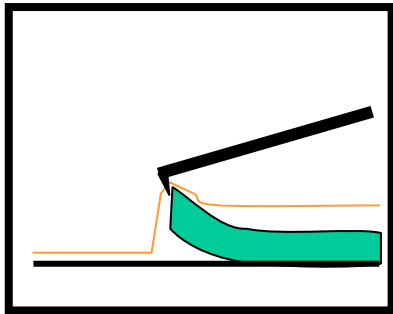


# AC imaging mode

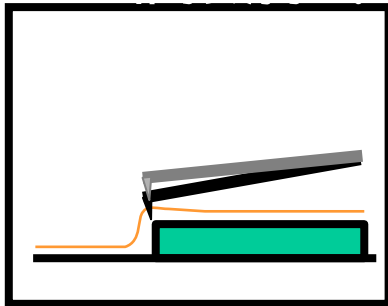
$$\omega_1 = \omega_0 (1 - F'/2c)$$



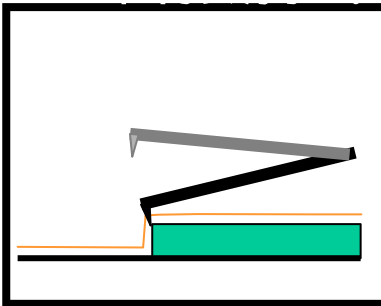
# Comparison of three scanning modes



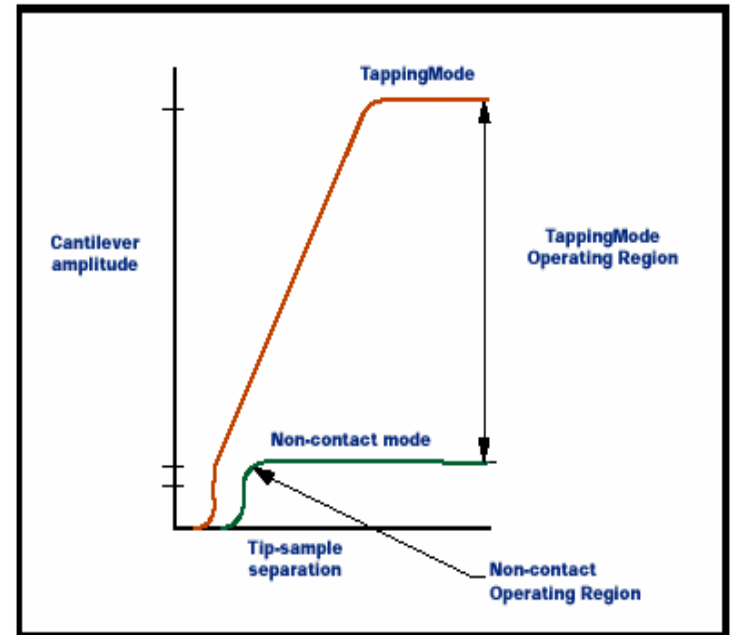
Contact



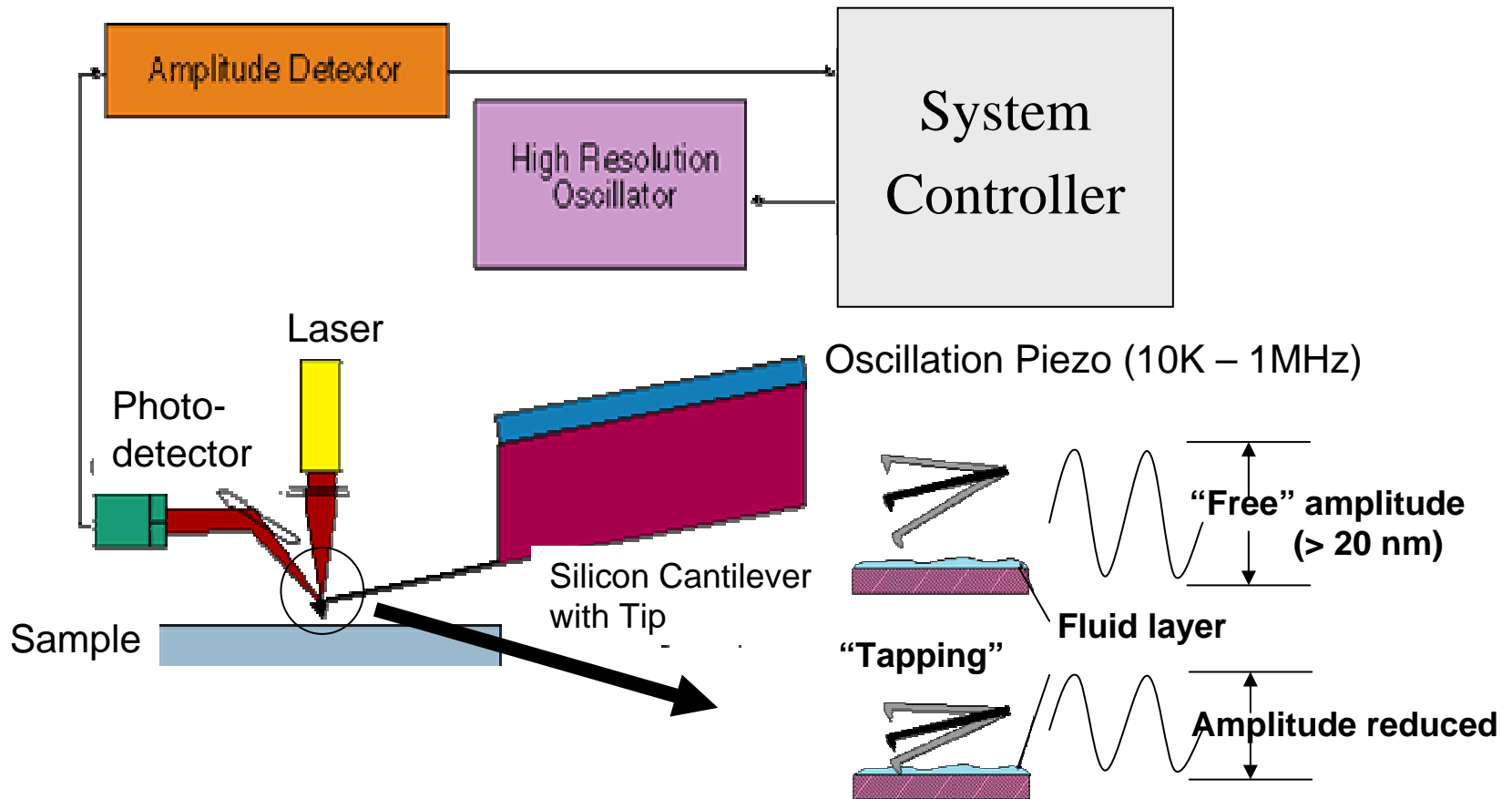
Non-contact



Intermittent-contact

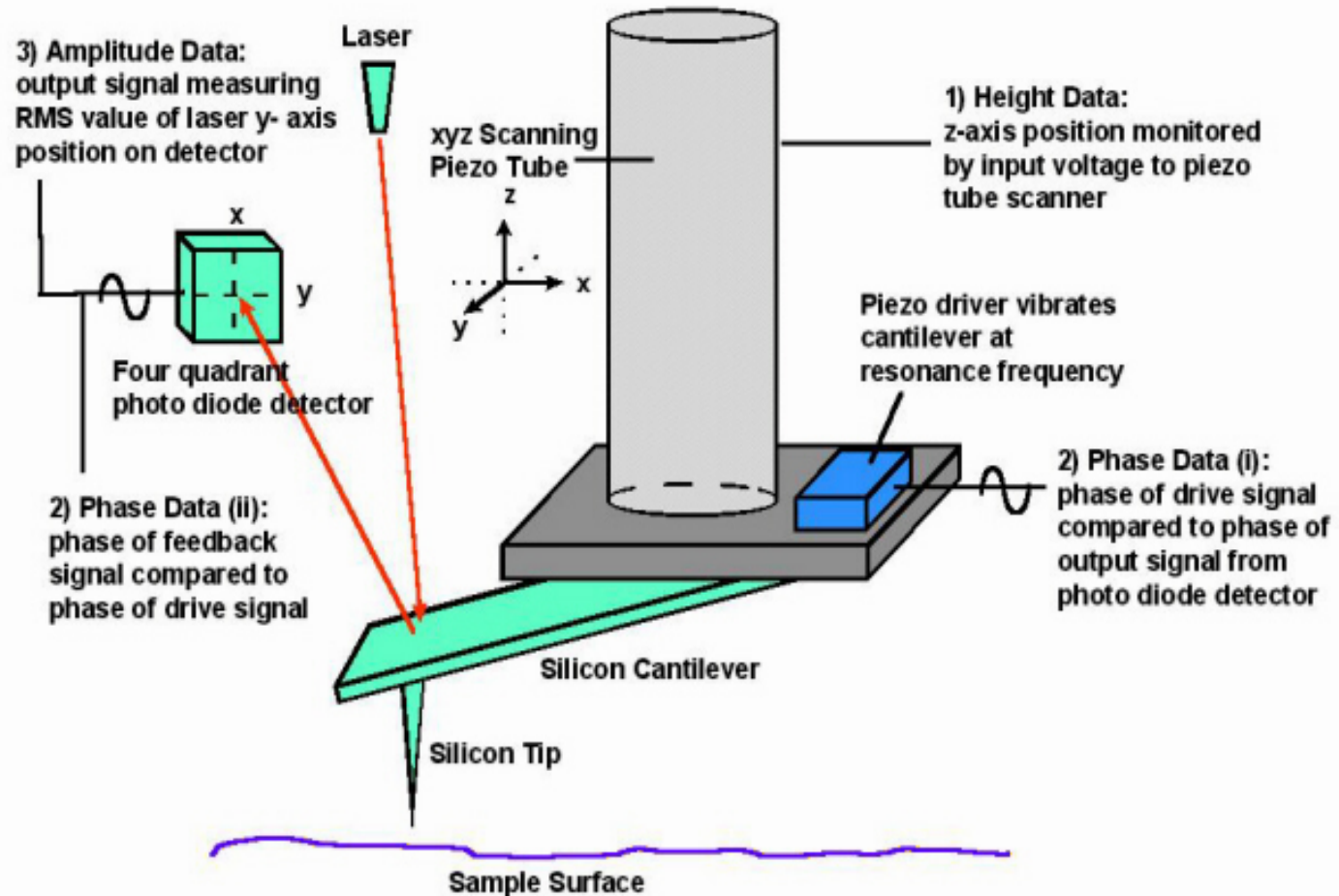


# Tapping mode

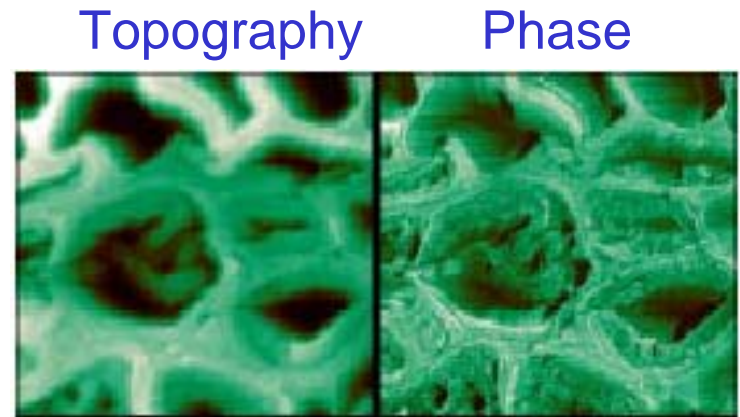
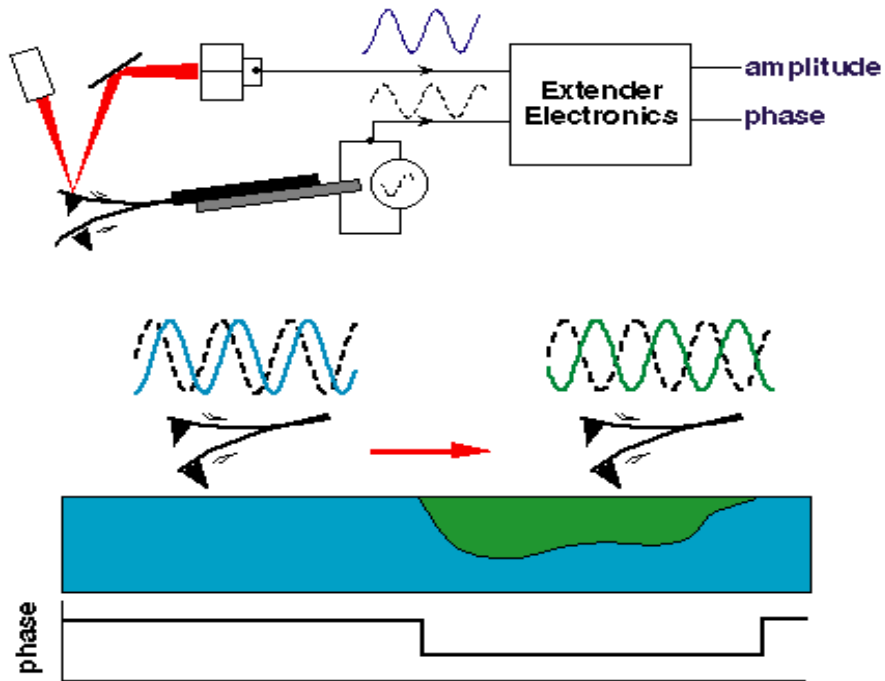




# Three Types of Data Collected in Tapping Mode

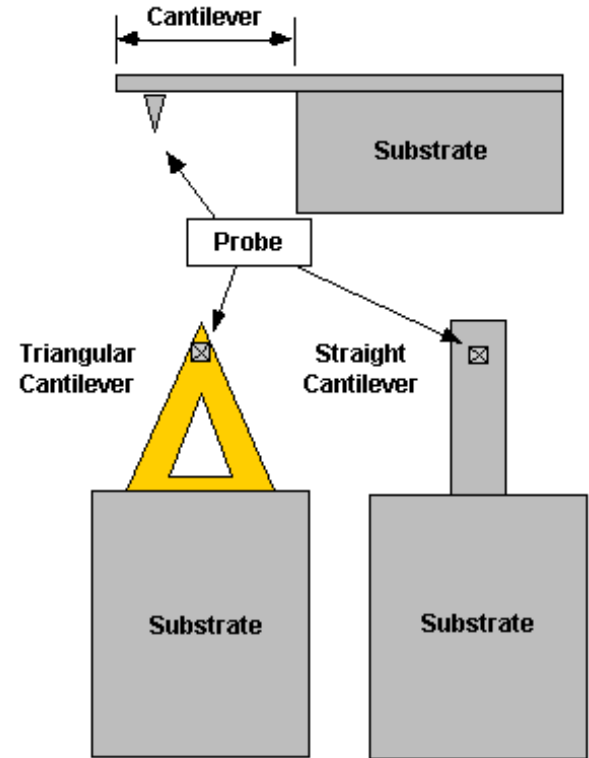
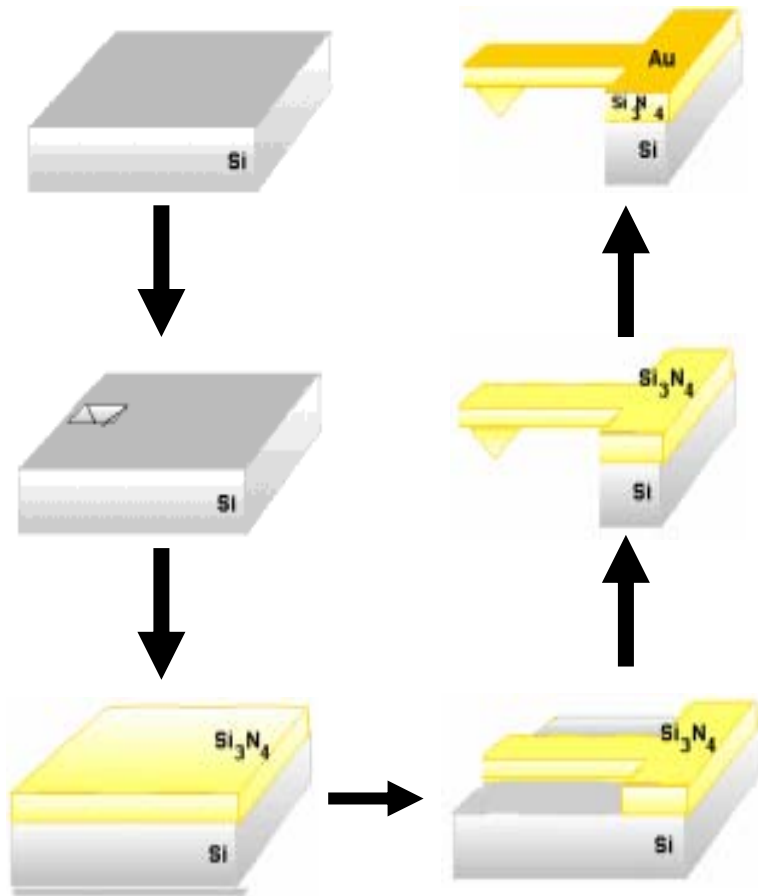


# Images by tapping mode



AFM image of a fresh  
Alfalfa root section

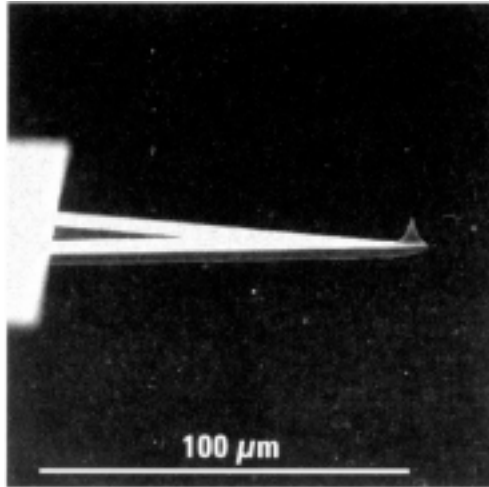
# Fabrication of AFM probes



Typical Tip Dimension:  $150\mu\text{m} \times 30\mu\text{m} \times 0.5\mu\text{m}$   
 $k \sim 0.1 \text{ N/m}$   
 Materials:  $\text{Si}_3\text{N}_4$

Typical Tip Dimension:  $150\mu\text{m} \times 30\mu\text{m} \times 3\mu\text{m}$   
 $f_r \sim 100 \text{ kHz}$   
 Materials: Si

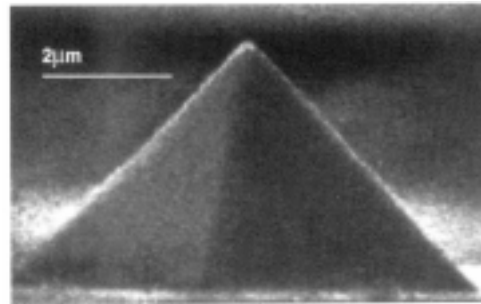
**V-shaped**



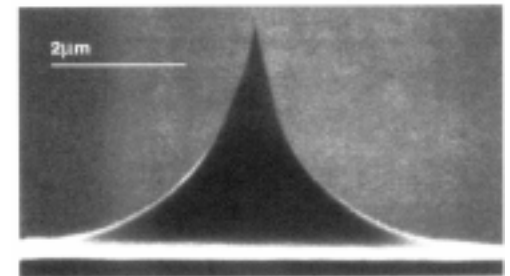
Materials: Si, SiO<sub>2</sub>, Si<sub>3</sub>N<sub>4</sub>

Ideal Tips: hard, small radius of curvature, high aspect ratio

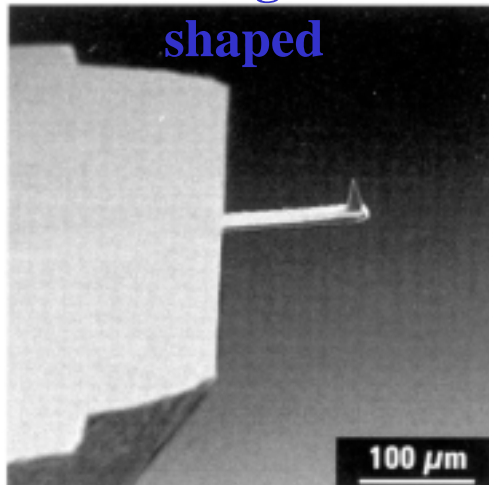
**Pyramid Tip**



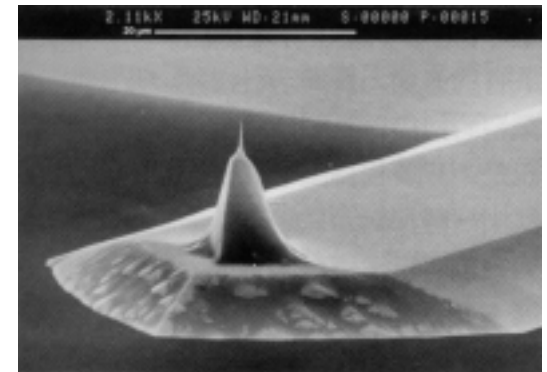
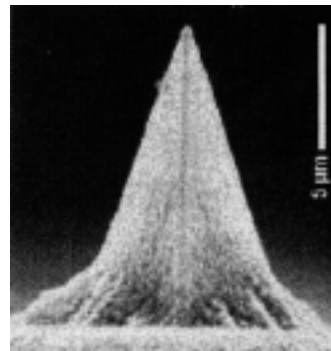
**Ultrasharp Tip**



**Rectangular-shaped**



**Diamond-coated Tip**



# Criteria for AFM probe

- 1) Small spring constant ( $k$ )       $F = k \Delta z$

To detect force of  $\sim$  nN

- 2) High resonant frequency ( $f_r$ )       $f_r \propto (k/m)^{1/2}$

To enable scanning and other operations

- 3) Highly anisotropic stiffness

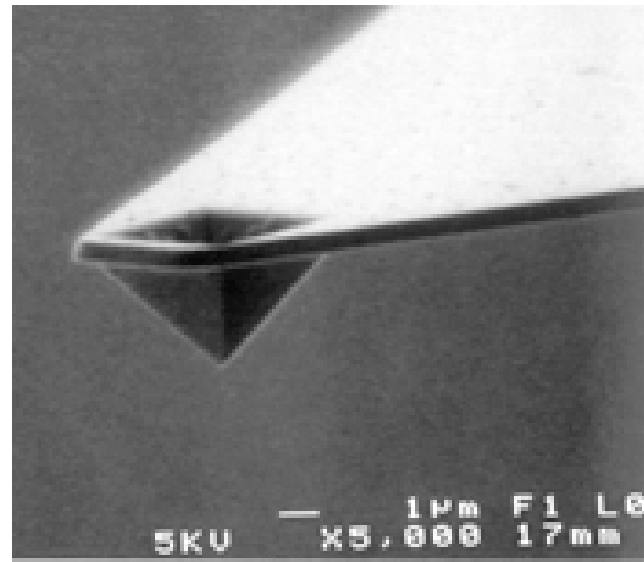
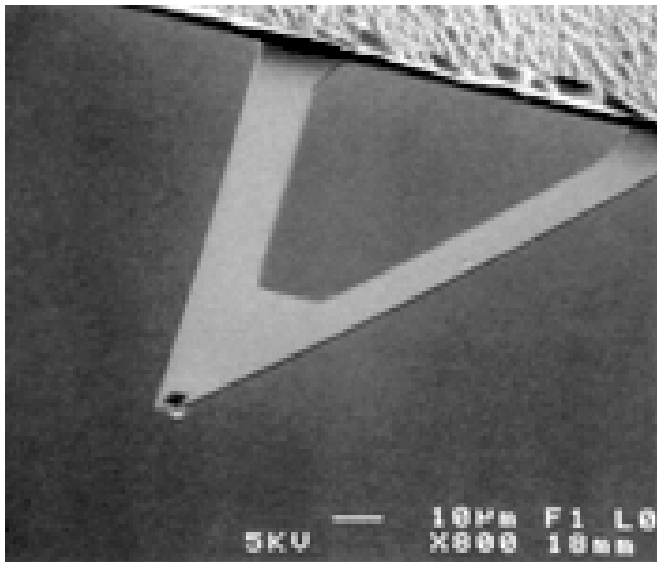
Easy to bent and difficult to twist

- 4) Sharp protrusion at the apex

To better define the tip-sample interaction

# Tip of small shear force

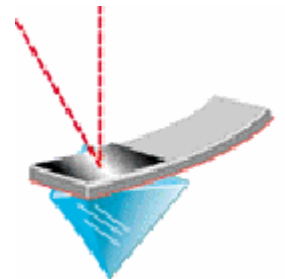
(for Contact mode)



Typical Tip Dimension:  
150µm x 30µm x 0.5µm

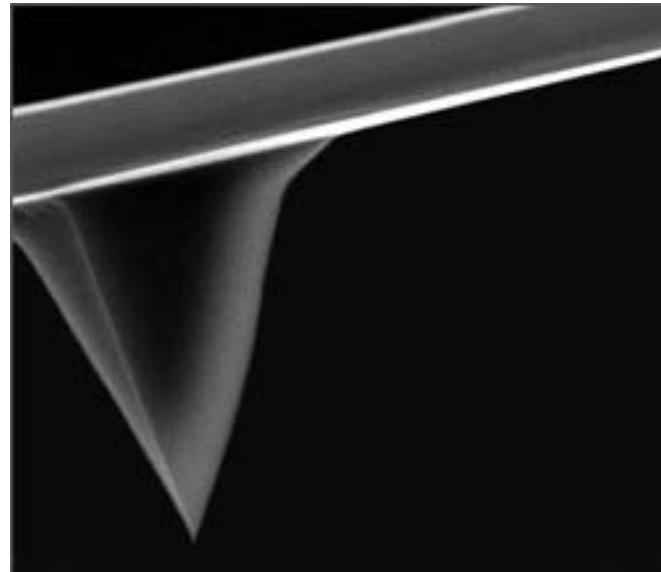
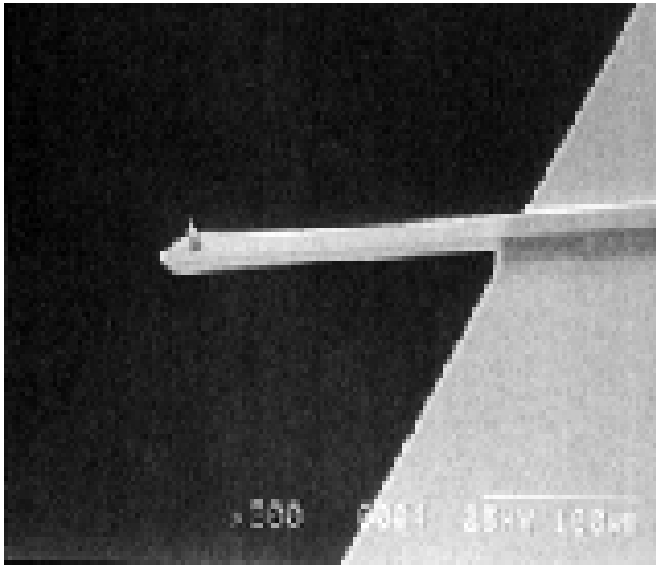
$k \sim 0.1 \text{ N/m}$

Materials:  $\text{Si}_3\text{N}_4$



# Tip of high resonant frequency

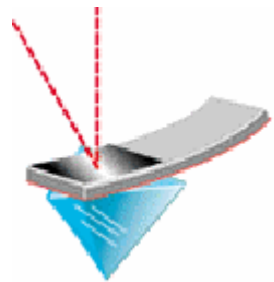
(for Tapping mode)



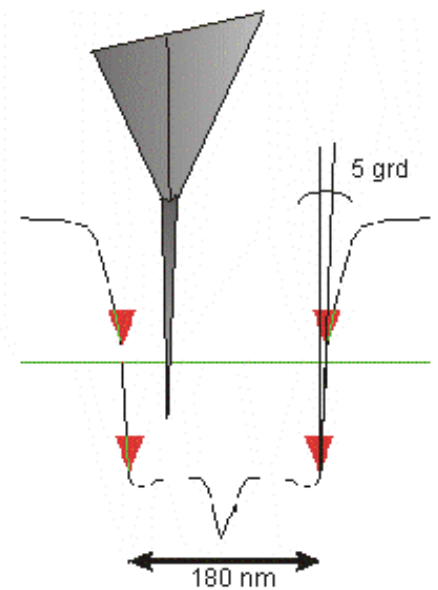
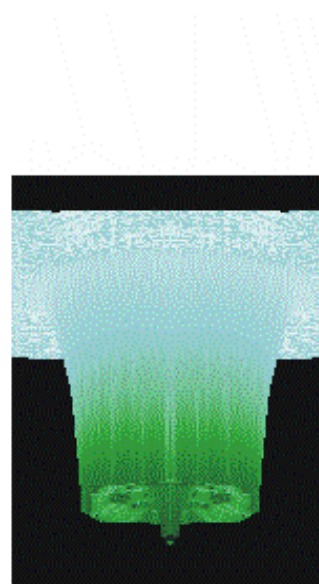
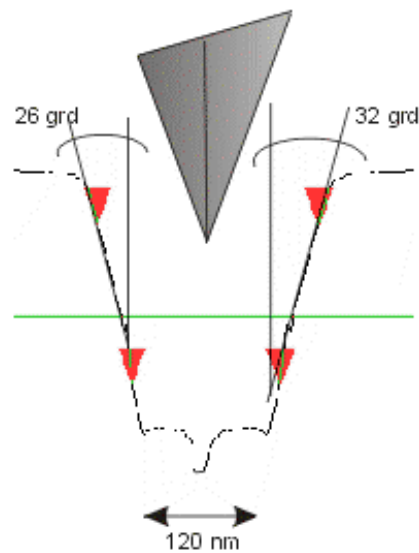
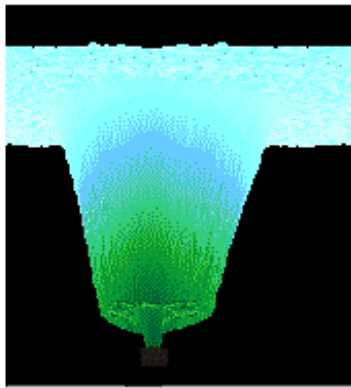
Typical Tip Dimension:  
 $150\mu\text{m} \times 30\mu\text{m} \times 3\mu\text{m}$

$f_r \sim 100 \text{ kHz}$

Materials: Si

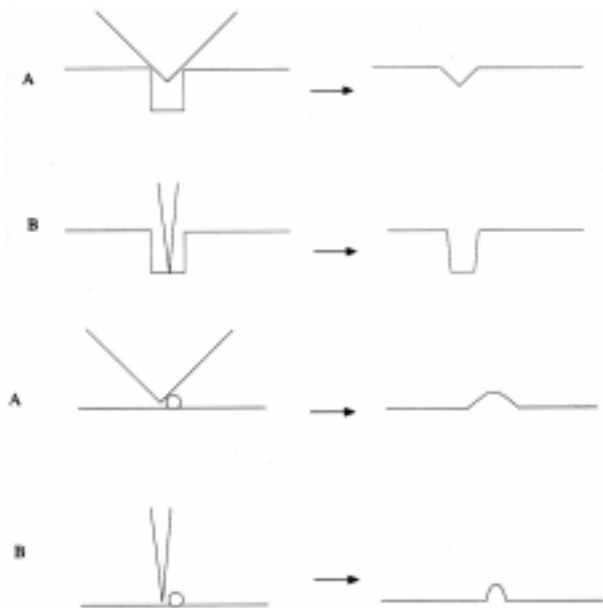
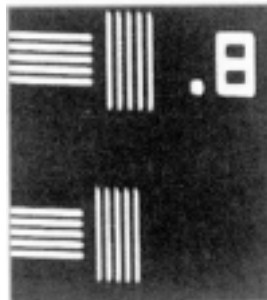
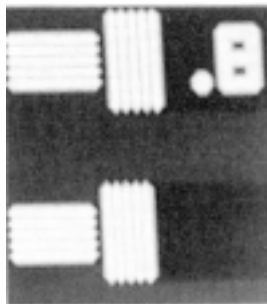
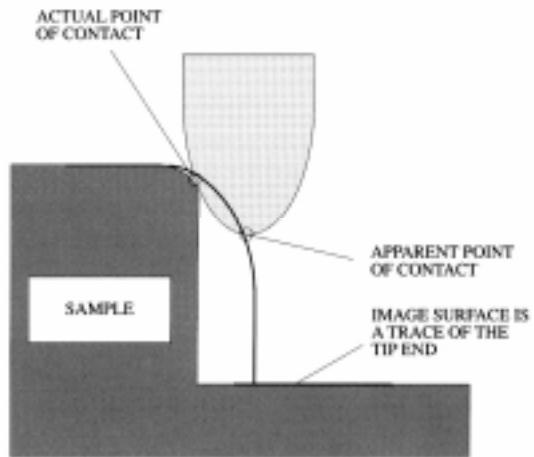


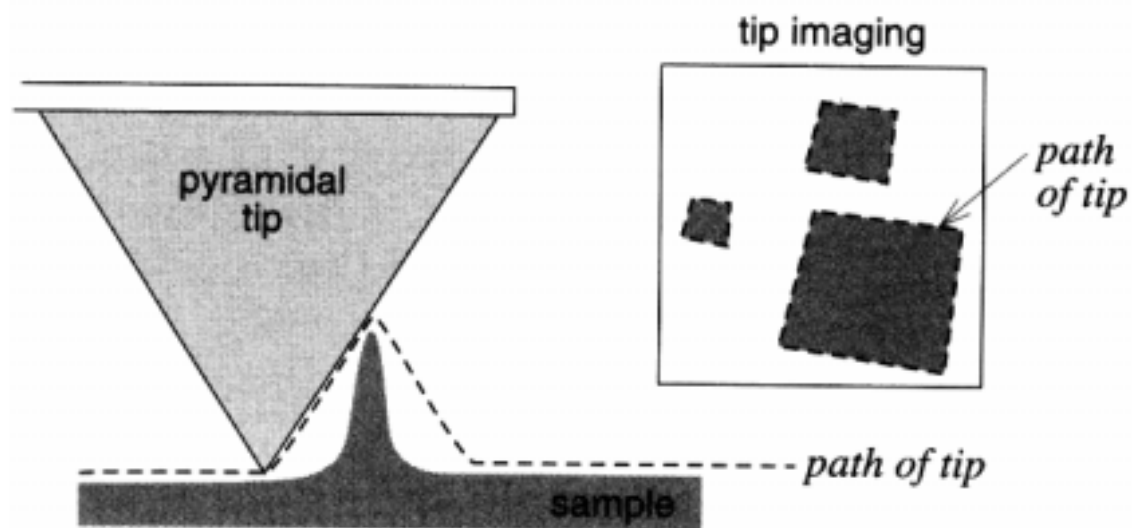
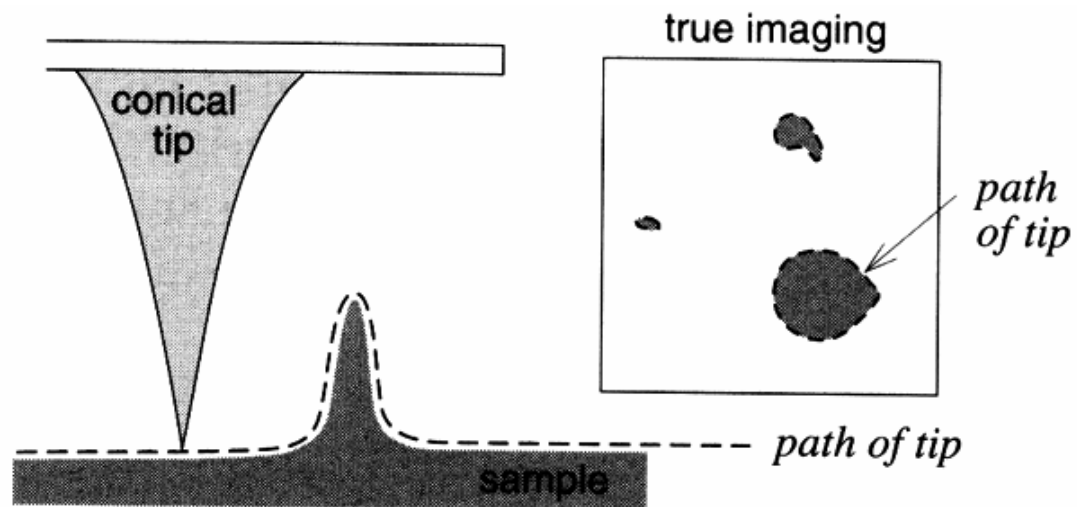
# Ultra-sharp tip



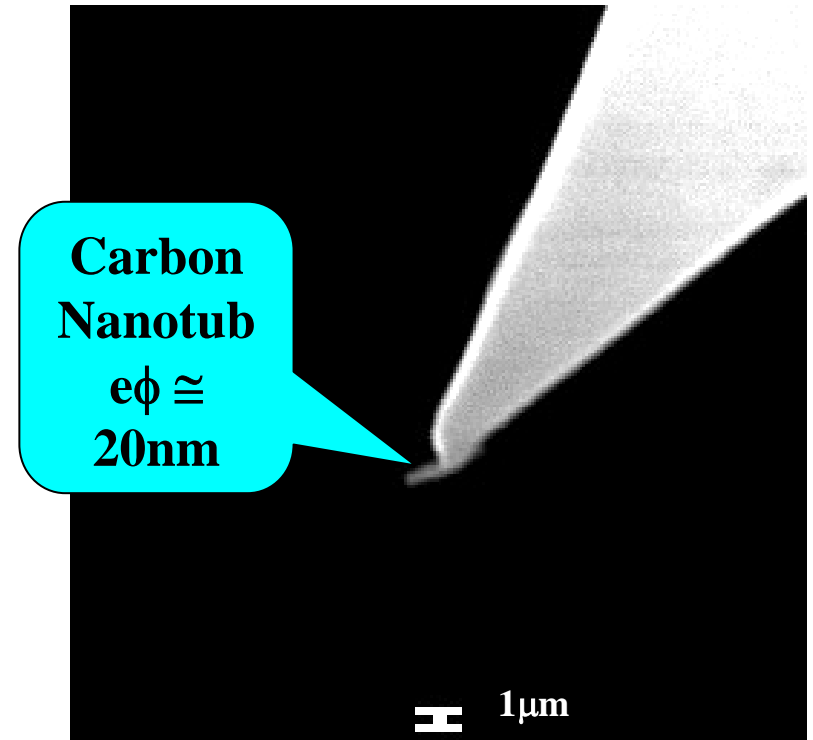
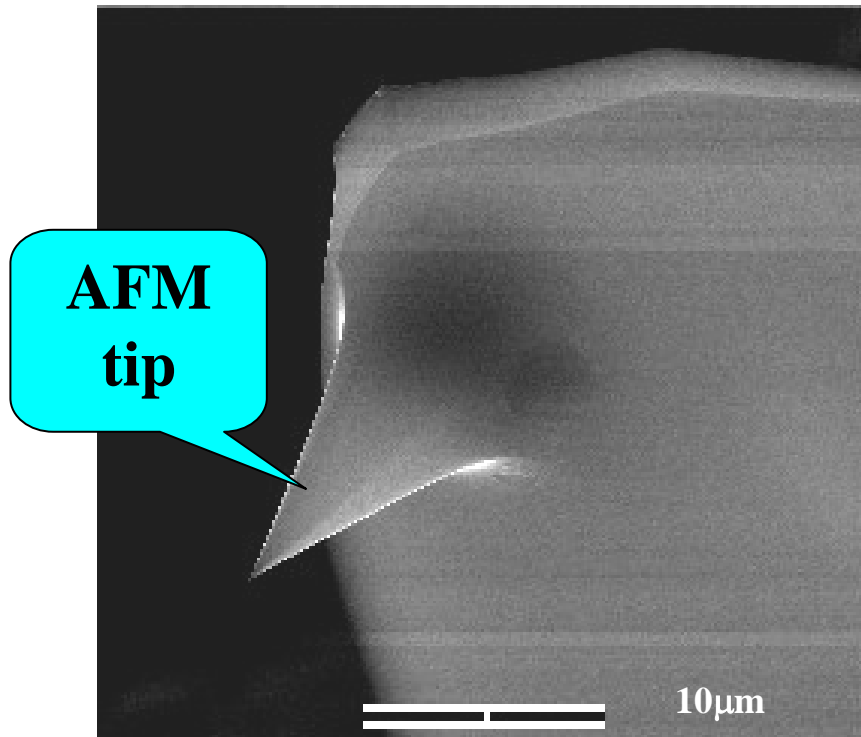


# Effects of the Tip Shape

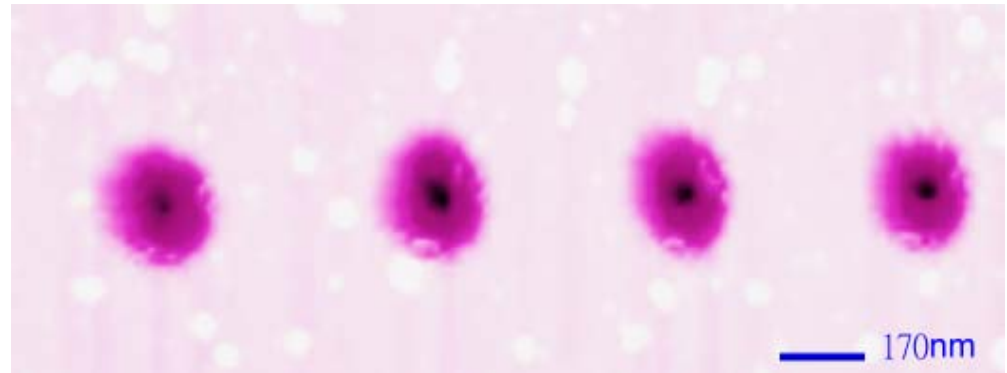




# AFM Tip + Carbon Nanotube

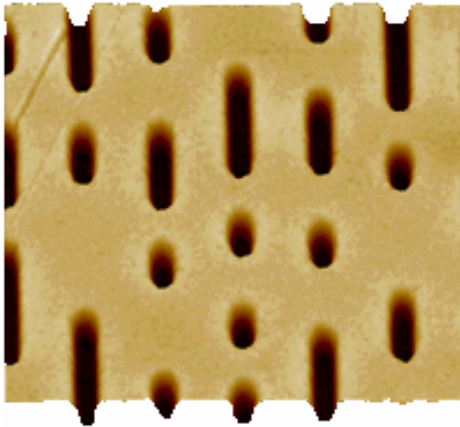


# Image of high aspect ratio

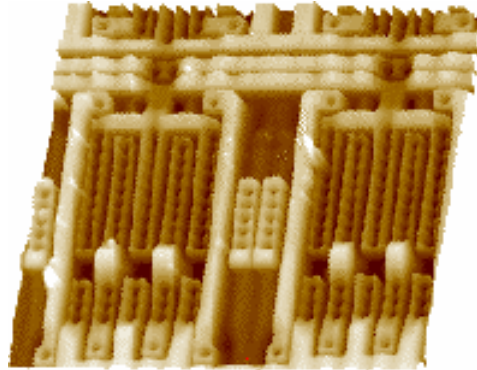


# AFM images

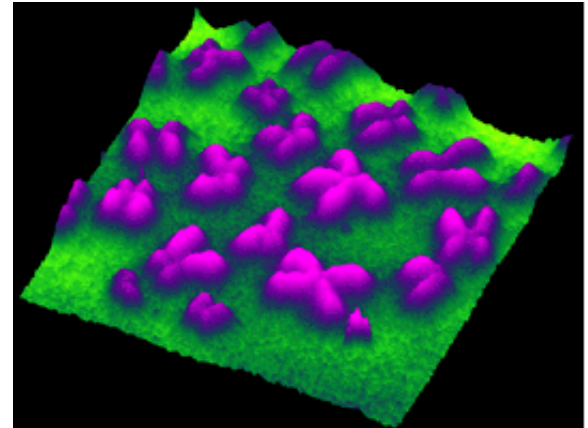
CD pits



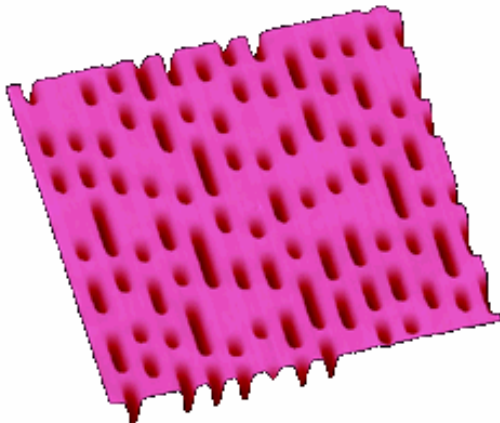
Integrated circuit



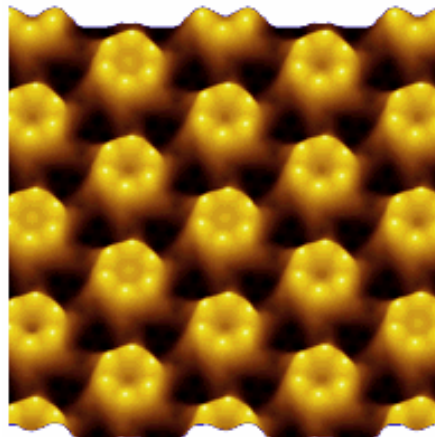
Chromosomes



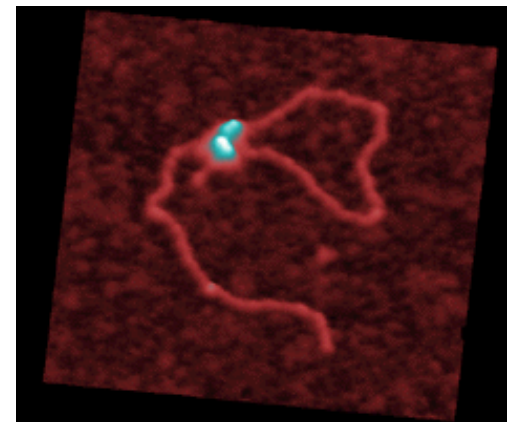
DVD pits



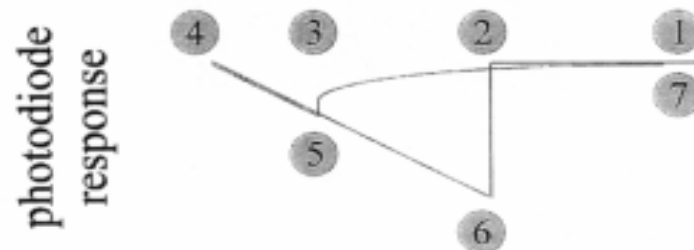
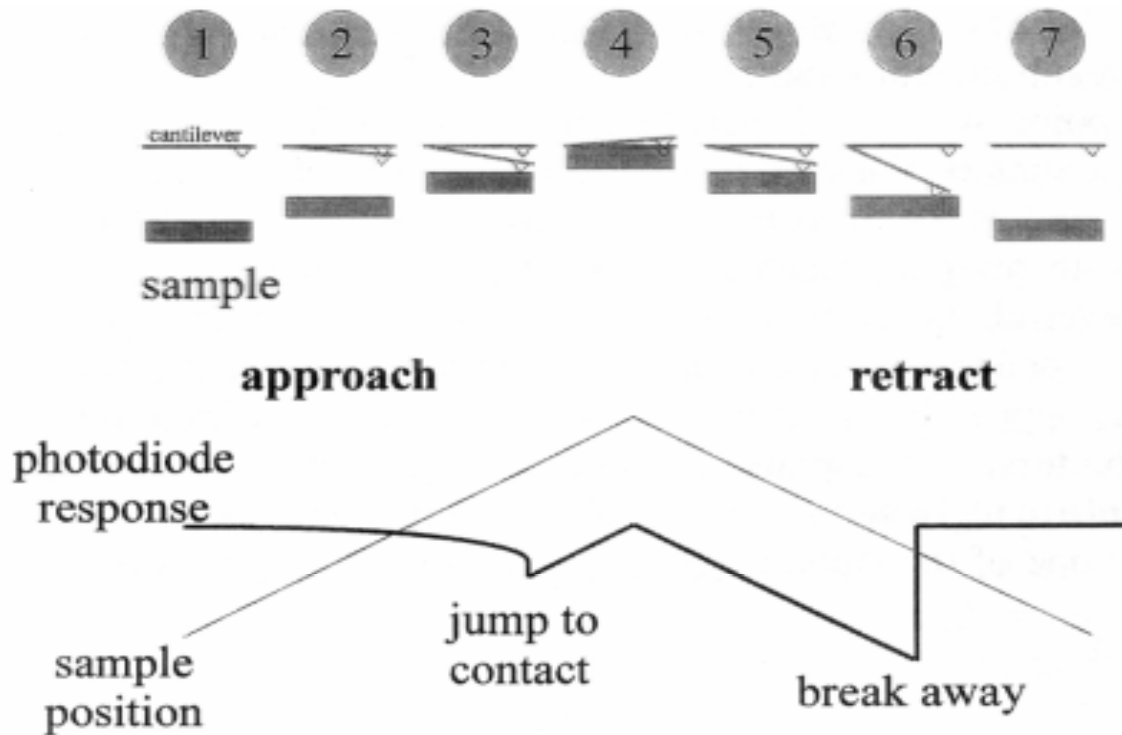
Bacteria



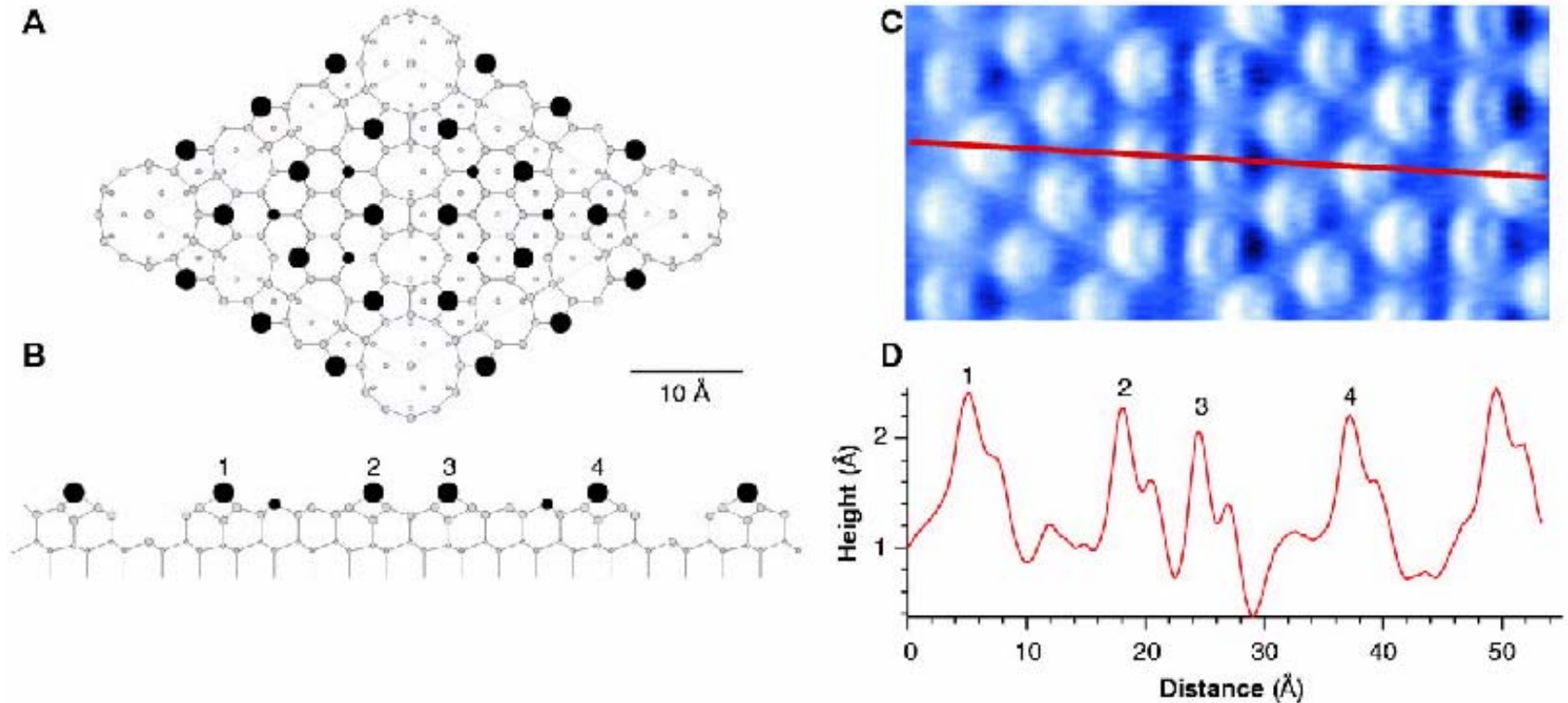
DNA



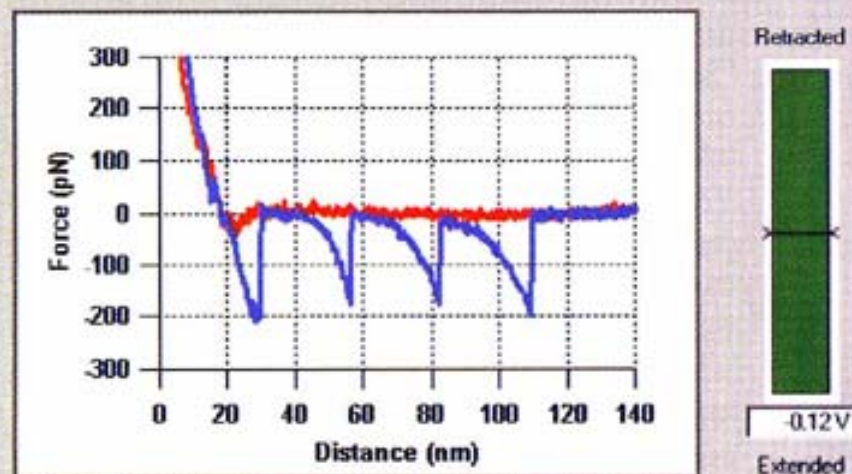
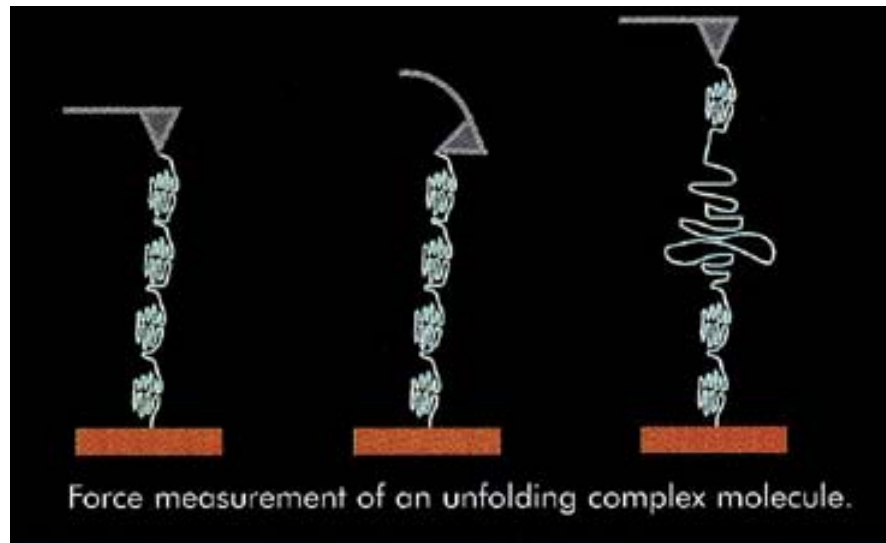
# Force-Distance Curve



# Atomic Image of Si(111)-(7×7) Taken with AFM



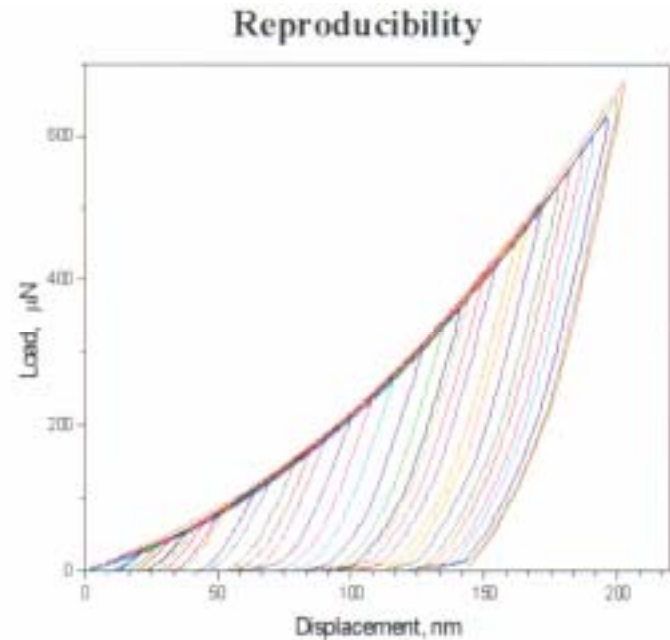
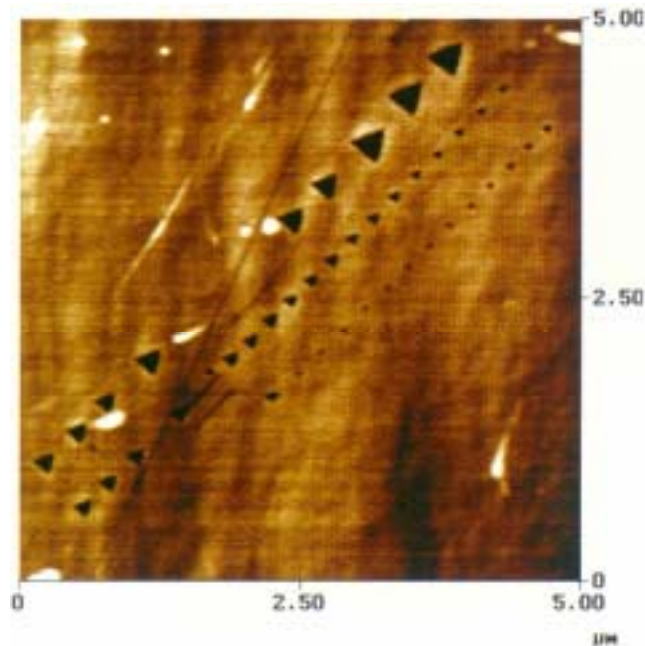
**F.J. Giessibl *et al.*, Science 289, 422 (2000)**



Advanced graphical user interface shows titin muscle molecule force curve.

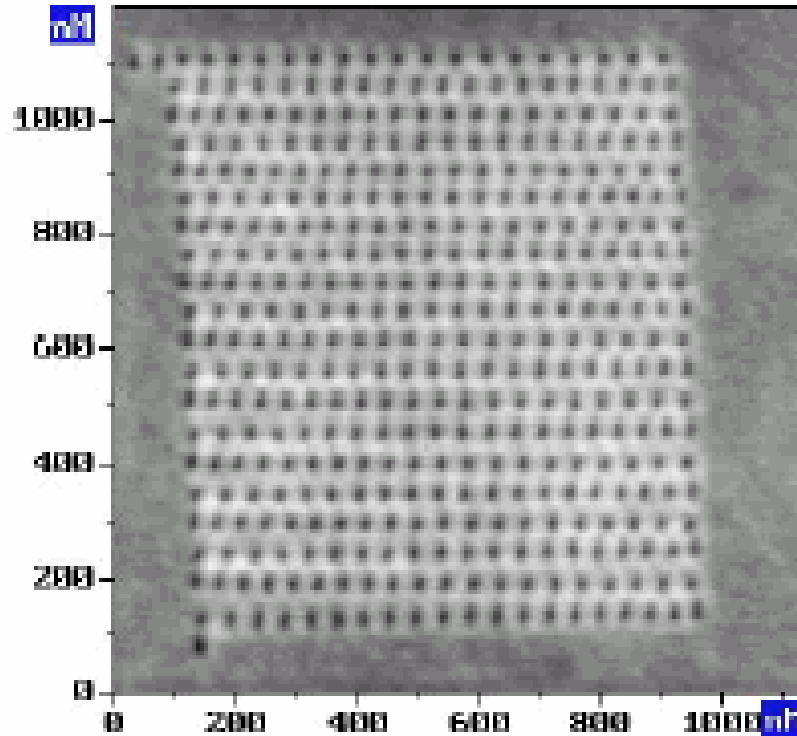


# Measurement of Mechanical Properties

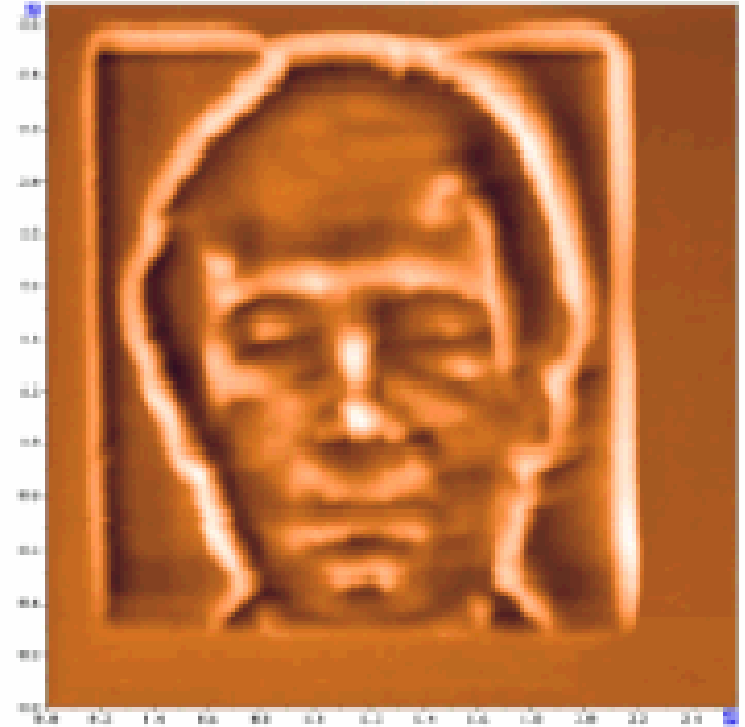


1. The load-displacement curves provide a “mechanical fingerprint” of material’s response to deformation, from which parameters such as hardness and young’s modulus of elasticity can be determined.
2. In measuring the mechanical properties of thin coated system, the size of contact impression should be kept small relative to the film thickness.

# Nanolithography of Tapping-Mode AFM



$(1.2 \mu\text{m} \times 1.2 \mu\text{m})$



$(2.5 \mu\text{m} \times 2.5 \mu\text{m})$

**Image of polycarbonated film on silicon surface**

7,000,000-YEAR-OLD SKULL: ANCESTOR? APE? OR DEAD END?

# SCIENTIFIC AMERICAN

The  
Nose-Tickling  
Science  
of Bubbly



JANUARY 2003  
WWW.SCIAM.COM

Micromachines Rewrite the Future  
of Data Storage

## The NANODRIVE

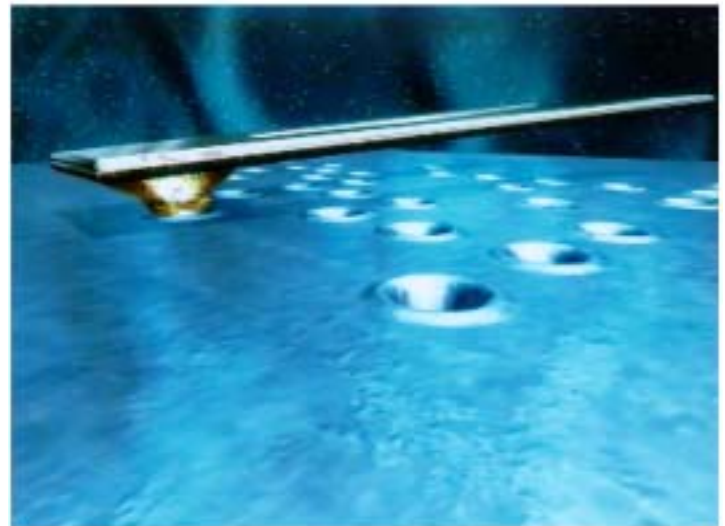
PREDICTING  
EARTHQUAKES

FIGHTING CANCER  
WITH LIGHT

THE GOVERNMENT'S  
FLAWED DIET ADVICE

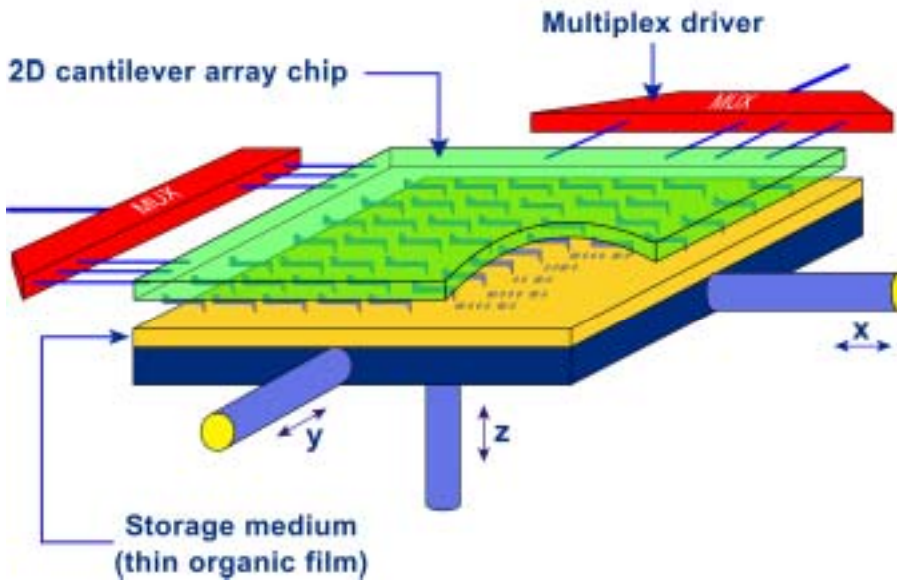


\$4.95 U.S. £2.95



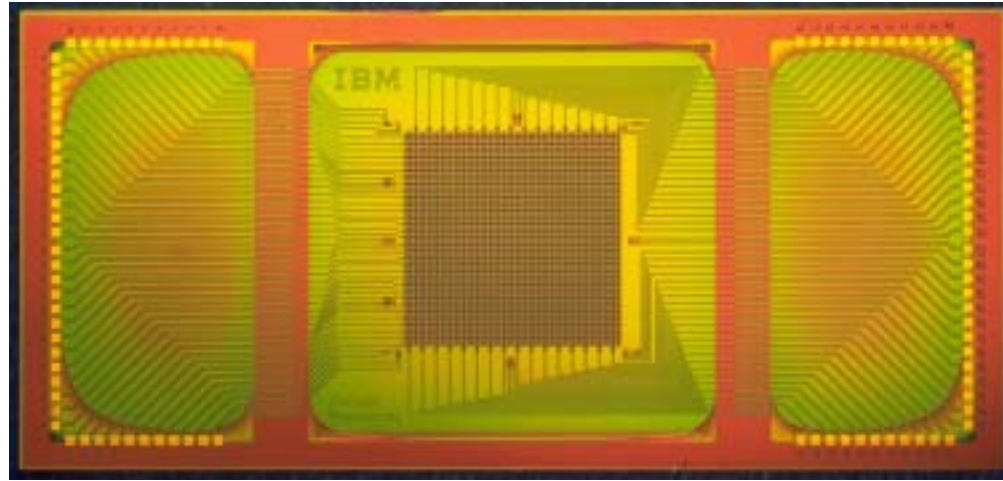
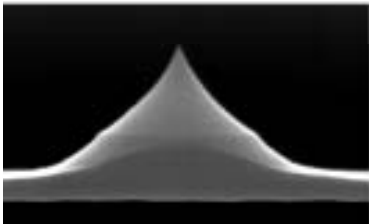
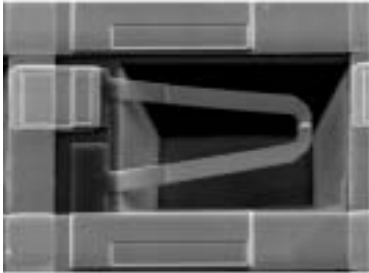
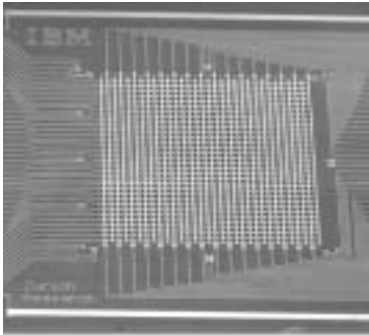
## "MILLIPEDE"

## Highly parallel, very dense AFM data storage system



**The Millipede concept:** for operation of the device, the storage medium - a thin film of organic material (yellow) deposited on a silicon "table" - is brought into contact with the array of silicon tips (green) and moved in x- and y-direction for reading and writing. Multiplex drivers (red) allow addressing of each tip individually.





**The Millipede chip:** the image shows the electrical wiring for addressing the 1,024 tips etched out in a square of 3mm by 3mm (center). The chip's size is 7 mm by 14 mm.

**Millipede cantilevers and tips:** electron microscope views of the 3 mm by 3 mm cantilever array (top), of an array section of 64 cantilevers (upper center), an individual cantilever (lower center), and an individual tip (bottom) positioned at the free end of the cantilever which is 70 micrometers (thousands of a millimeter) long, 10 micrometers wide, and 0.5 micrometers thick. The tip is less than 2 micrometers high and the radius at its apex smaller than 20 nanometers (millionths of a millimeter).